



Form PTO-1449 (Modified)	Atty. Docket No.:	Serial No.:
	F0611	09 903.884
	Applicants: Halliyal, et al.	
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary.)	Filing Date:	Group:
	July 12, 2001	2877

REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Partial Translation	
						Yes	No

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

	~ 5	Niu, X., et al., "Specular Spectroscopic Scatterometry in DUV Lithography," Timbre Technology, Inc., et al
	~ 3	Smith, T., et al., "Process Control in the Semiconductor Industry," http://www.mit.edu/taber/Research/Process_Control/IFRC99 pp1-24
	~ 5	Cote, D.R., et al., "Plasma-assisted chemical vapor deposition of dielectric thin films for ULSI semiconductor circuits," IBM Journal of Research & Development, Vol. 43, No. 1, pp 1-30

EXAMINER	DATE CONSIDERED
<i>[Signature]</i>	<i>2 July 2001</i>

EXAMINER Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Information Disclosure Statement PTO-1449 (Modified)

The identification of any reference is not intended to be, and should not be understood as being, an admission that such publication, in fact, constitutes prior art within the meaning of applicable law since, for example, a given reference may have a later effective date than it so seems apparent or the reference may have an effective date which can be antedated. The prior art status of any reference is a matter to be resolved during prosecution.